BB

MICROWAVE INTEGRATED CIRCUIT MEASUREMENTS

Chairman: Harry M. Cronson—The MITRE Corporation

Session Abstract: On-wafer probe measurements and large-signal IC characterizations are now accepted techniques. These reduce the cost of MMIC testing and provide more accurate linear and non-linear parameters. The first paper describes a promising non-contacting probe for measurements at arbitrary points within the circuit. The next paper examines various factors contributing inaccuracies in on-wafer noise measurements. Two aspects of large signal measurements are tested in the remaining two papers. The first describes an on-wafer pulsed system to extract several non-linear characteristics. The other obtains 40 GHz load-pull characteristics of a transistor in a fixture by electronically varying the output load impedance. This session should encourage workers to develop faster and more accurate on-wafer probe measurements.

4:00 p.m.–5:30 p.m., Wednesday, June 14, 1989
Pacific Room